

<b>FORM 1449</b> <b>INFORMATION DISCLOSURE STATEMENT</b> <b>IN AN APPLICATION</b> (Use several sheets if necessary)	Docket Number: 10467.43US12	Application Number: 10/751,091
	Applicant: MOECKLY ET AL.	
	Filing Date: 01/02/2004	Group Art Unit: 1755

U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>PN</i>	2004/0134967 A1	07/15/2004	Moeckly et al.			

FOREIGN PATENT DOCUMENTS							
	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)		
<i>PN</i>		Char, K. et al., "High $T_c$ superconductor-normal-superconductor Josephson junctions using $\text{CaRuO}_3$ as the metallic barrier," <i>Applied Physics Letters</i> , Vol. 62, No. 2, pp. 196-198 (January 11, 1993)
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		Huang, Y. et al., "The effect of microstructure on the electrical properties of YBCO interface-engineered Josephson junctions," <i>Physica C</i> , Vol. 314, pp. 36-42 (1999)
		Makita, T. et al., "Fabrication of Ramp-Edge Junction with $\text{NdBa}_2\text{Cu}_3\text{O}_y$ -Based Interface-Modified Barrier," <i>Jpn. J. Appl. Phys.</i> , Vol. 39, Part 2, No. 7B, pp. L730-L732 (July 15, 2000)
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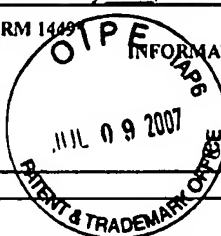
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EXAMINER <i>Paul W. [Signature]</i>	DATE CONSIDERED <i>07/17/07</i>
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FORM 1449 INFORMATION DISCLOSURE STATEMENT IN AN APPLICATION (Use several sheets if necessary)	Docket Number: 10467.43US12	Application Number: 10/751,091
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M	4,916,116	04/10/1990	Yamazaki			
	4,943,558	07/24/1990	Soltis et al.			
	5,077,270	12/31/1991	Takeda et al.			
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	5,904,861	05/1999	Ban et al.			

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DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
					YES	NO
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<i>PW</i>	Hunt, B. et al., "High Temperature Superconductor Josephson Weak Links", <i>Second Symposium on Low Temperature Electronics and High Temperature Superconductivity, Electrochemical Society Meeting, Honolulu, Hawaii</i> , Vol. 93-22, pp. 467-472 (May 1993).
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


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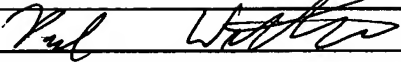
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